Joan Esteve

List of Publications by Year in Descending Order

118 papers	2,946 citations	33 h-index	47 g-index
120 ext. papers	3,090 ext. citations	3.7 avg, IF	4.6 L-index

#	Paper	IF	Citations
118	Low Wear and Low Friction DLC Coating With Good Adhesion to CoCrMo Metal Substrates. *Physica Status Solidi (B): Basic Research*, **2018**, 255, 1800225	1.3	2
117	Ultra low nanowear in novel chromium/amorphous chromium carbide nanocomposite films. *Applied Surface Science*, **2017**, 420, 707-713	6.7	14
116	Enhanced reactivity of high-index surface platinum hollow nanocrystals. *Journal of Materials Chemistry A*, **2016**, 4, 200-208	13	30
115	Influence of the microstructure on the thermal shock behavior of cemented carbides. *Ceramics International*, **2016**, 42, 12701-12708	5.1	20
114	Substrate surface finish effects on scratch resistance and failure mechanisms of TiN-coated hardmetals. *Surface and Coatings Technology*, **2015**, 265, 174-184	4.4	20
113	Exploring New Synthetic Strategies for the Production of Advanced Complex Inorganic Nanocrystals. *Zeitschrift Fur Physikalische Chemie*, **2015**, 229,	3.1	5
112	Improvement of the Electrochemical Behavior of Steel Surfaces Using a [Ti-Al/Ti-Al-N] n Multilayer System. *Journal of Materials Engineering and Performance*, **2013**, 22, 1471-1480	1.6	4
111	MECHANICAL AND TRIBOLOGICAL BEHAVIOR OF VN AND HfN FILMS DEPOSITED VIA REACTIVE MAGNETRON SPUTTERING. *Surface Review and Letters*, **2013**, 20, 1350040	1.1	14
110	Developing plating baths for the production of reflective Ni□Cu films. *Electrochimica Acta*, **2012**, 62, 381-389	3.7	25
109	Effect of the bias voltage on the structure of nc-CrC/a-C:H coatings with high carbon content. *Surface and Coatings Technology*, **2012**, 206, 2877-2883	4.4	25
108	Study of magnetic and structural properties of ferrofluids based on cobalt□inc ferrite nanoparticles. *Journal of Magnetism and Magnetic Materials*, **2012**, 324, 394-402	2.8	51
107	Improvement of mechanical and tribological properties in steel surfaces by using titanium□luminum/titanium□luminum nitride multilayered system. *Applied Surface Science*, **2012**, 258, 3805-3814	6.7	41
106	Corrosion surface protection by using titanium carbon nitride/titanium□iobium carbon nitride multilayered system. *Thin Solid Films*, **2011**, 519, 6362-6368	2.2	10
105	Enhancement of surface mechanical properties by using TiN[BCN/BN]n/c-BN multilayer system. *Applied Surface Science*, **2010**, 257, 1098-1104	6.7	14
104	Control of the bias voltage in d.c. PVD processes on insulator substrates. *Vacuum*, **2009**, 83, 1287-1290	3.7	7
103	Influence of deposition pressure on the structural mechanical and decorative properties of TiN thin films deposited by cathodic arc evaporation. *Vacuum*, **2007**, 81, 1507-1510	3.7	20
102	Surface and optical analysis of SiCx films prepared by RF-RMS technique. *Diamond and Related Materials*, **2006**, 15, 71-79	3.5	10

101	CrAlN coatings deposited by cathodic arc evaporation at different substrate bias. *Thin Solid Films*, **2006**, 515, 113-117	2.2	80
100	Tribological performance of chromium/chromium carbide multilayers deposited by r.f. magnetron sputtering. *Surface and Coatings Technology*, **2005**, 200, 1819-1824	4.4	17
99	Growth vs. nucleation of conducting polymers thin films obtained by plasma-enhanced chemical vapor deposition. *Thin Solid Films*, **2004**, 451-452, 74-80	2.2	19
98	Mechanical strength improvement of electrical discharge machined cemented carbides through PVD (TiN, TiAlN) coatings. *Thin Solid Films*, **2004**, 447-448, 258-263	2.2	21
97	Nanometric chromium nitride/chromium carbide multilayers by r.f. magnetron sputtering. *Surface and Coatings Technology*, **2004**, 180-181, 335-340	4.4	38
96	Mechanical properties of nanocomposite and multilayered CrSiN sputtered thin films. *Surface and Coatings Technology*, **2004**, 180-181, 570-574	4.4	101
95	Period dependence of hardness and microstructure on nanometric Cr/CrN multilayers. *Surface and Coatings Technology*, **2004**, 188-189, 338-343	4.4	42
94	Cathodic chromium carbide coatings for molding die applications. *Surface and Coatings Technology*, **2004**, 188-189, 506-510	4.4	55
93	Preparation and nanoscale mechanical properties of self-assembled carboxylic acid functionalized pentathiophene on mica. *Langmuir*, **2004**, 20, 7703-10	4	24
92	Nanoindentation stress–strain curves as a method for thin-film complete mechanical characterization: application to nanometric CrN/Cr multilayer coatings. *Applied Physics A: Materials Science and Processing*, **2003**, 77, 419-426	2.6	68
91	Effects of carbon incorporation in tungsten carbide films deposited by r.f. magnetron sputtering: single layers and multilayers. *Surface and Coatings Technology*, **2003**, 163-164, 386-391	4.4	33
90	Wear behavior of nanometric CrN/Cr multilayers. *Surface and Coatings Technology*, **2003**, 163-164, 571-577	4.4	82
89	Properties of a-C:H films deposited from a methane electron cyclotron wave resonant plasma. *Current Applied Physics*, **2003**, 3, 433-437	2.6	5
88	Nanometric chromium/chromium carbide multilayers for tribological applications. *Surface and Coatings Technology*, **2003**, 163-164, 392-397	4.4	48
87	Diamond coatings on electrical-discharge machined hardmetals. *Diamond and Related Materials*, **2003**, 12, 762-767	3.5	4
86	Micromechanical properties of carbon–silica aerogel composites. *Applied Physics A: Materials Science and Processing*, **2002**, 74, 119-122	2.6	18
85	Tribological performance of TiN supported molybdenum and tantalum carbide coatings in abrasion and sliding contact. *Wear*, **2002**, 253, 1182-1187	3.5	33
84	Mechanical strengthening in nanometric CrN/Cr multilayers measured by nanoindentation. *Journal Physics D: Applied Physics*, **2002**, 35, 1880-1883	3	14

83	Nanoindentation hardness measurements using real-shape indenters: application to extremely hard and elastic materials. *Applied Physics A: Materials Science and Processing*, **2001**, 72, 319-324	2.6	9
82	Influence of thickness on the properties of hydroxyapatite coatings deposited by KrF laser ablation. *Biomaterials*, **2001**, 22, 2171-5	15.6	66
81	Tungsten carbide/diamond-like carbon multilayer coatings on steel for tribological applications. *Surface and Coatings Technology*, **2001**, 148, 277-283	4.4	75
80	Multilayered chromium/chromium nitride coatings for use in pressure die-casting. *Surface and Coatings Technology*, **2001**, 146-147, 268-273	4.4	69
79	Influence of electrical discharge machining on the sliding contact response of cemented carbides. *International Journal of Refractory Metals and Hard Materials*, **2001**, 19, 35-40	4.1	32
78	Analysis of diamond nucleation on molybdenum by biased hot filament chemical vapor deposition. *Diamond and Related Materials*, **2001**, 10, 383-387	3.5	13
77	Micromechanical and microtribological properties of BCN thin films near the B4C composition deposited by r.f. magnetron sputtering. *Diamond and Related Materials*, **2001**, 10, 1892-1896	3.5	34
76	Study of the mechanical properties of tetrahedral amorphous carbon films by nanoindentation and nanowear measurements. *Diamond and Related Materials*, **2001**, 10, 145-152	3.5	56
75	Amorphous SixC1⊠ films: an example of materials presenting low indentation hardness and high wear resistance. *Diamond and Related Materials*, **2001**, 10, 1053-1057	3.5	19
74	Protective coatings for Al metallizations obtained by plasma polymerization **2000**,		1
73	Mechanical properties of calcium phosphate coatings deposited by laser ablation. *Biomaterials*, **2000**, 21, 967-71	15.6	103
72	Mechanical and tribological properties of tungsten carbide sputtered coatings. *Thin Solid Films*, **2000**, 373, 282-286	2.2	46
71	Microtribological characterization of group V and VI metal-carbide wear-resistant coatings effective in the metal casting industry. *Surface and Coatings Technology*, **2000**, 133-134, 314-318	4.4	13
70	Mechanical properties of plasma deposited polymer coatings. *Surface and Coatings Technology*, **2000**, 125, 383-387	4.4	37
69	Surface analysis of nanostructured ceramic coatings containing silicon carbide nanoparticles produced by plasma modulation chemical vapour deposition. *Thin Solid Films*, **2000**, 377-378, 495-500	2.2	11
68	Improvement of hardness in plasma polymerized hexamethyldisiloxane coatings by silica-like surface modification. *Thin Solid Films*, **2000**, 377-378, 109-114	2.2	89
67	Step-by-step simulations of diamond nucleation and growth on a silicon (001) surface. *Diamond and Related Materials*, **2000**, 9, 146-155	3.5	1
66	BCN thin films near the B 4 C composition deposited by radio frequency magnetron sputtering. *Diamond and Related Materials*, **2000**, 9, 502-505	3.5	48

65	Plasma polymer thin films obtained by plasma polymerization of pyrrole. *European Physical Journal Special Topics*, **1999**, 09, Pr8-461-Pr8-469		1
64	Micromechanical properties of silica aerogels. *Applied Physics Letters*, **1999**, 75, 653-655	3.4	82
63	Diamond and diamond-like carbon films. *Vacuum*, **1999**, 52, 133-139	3.7	22
62	Surface treatment of titanium by Nd:YAG laser irradiation in the presence of nitrogen. *Applied Physics A: Materials Science and Processing*, **1999**, 69, S699-S702	2.6	20
61	Effect of ion bombardment on the properties of B4C thin films deposited by RF sputtering. *Thin Solid Films*, **1999**, 355-356, 210-213	2.2	18
60	Synthesis of cubic aluminum nitride by carbothermal nitridation reaction. *Diamond and Related Materials*, **1999**, 8, 1342-1344	3.5	35
59	Mechanism of diamond nucleation enhancement by electron emission via hot filament chemical vapor deposition. *Diamond and Related Materials*, **1999**, 8, 123-126	3.5	17
58	Substrate temperature effects on the microhardness and adhesion of diamond-like thin films. *Diamond and Related Materials*, **1999**, 8, 563-566	3.5	21
57	Micromechanical properties of BN and B□N coatings obtained by r.f. plasma-assisted CVD. *Diamond and Related Materials*, **1999**, 8, 423-427	3.5	35
56	Boron carbide thin films deposited by tuned-substrate RF magnetron sputtering. *Diamond and Related Materials*, **1999**, 8, 402-405	3.5	69
55	YSZ protective coatings elaborated by MOCVD on nickel-based alloys. *Surface and Coatings Technology*, **1998**, 100-101, 164-168	4.4	8
54	Hardness and morphological characterization of tungsten carbide thin films. *Surface and Coatings Technology*, **1998**, 108-109, 323-327	4.4	17
53	Piezoresistivity of p-type heteroepitaxial diamond films on Si(100). *Diamond and Related Materials*, **1998**, 7, 528-532	3.5	17
52	Preparation of B?C?N thin films by r.f. plasma assisted CVD. *Diamond and Related Materials*, **1998**, 7, 376-379	3.5	53
51	Nucleation of diamond on silicon by biased HFCVD: A comparative study. *Diamond and Related Materials*, **1998**, 7, 200-204	3.5	14
50	Growth of diamond films on boron nitride thin films by bias-assisted hot filament chemical vapor deposition. *Applied Physics Letters*, **1997**, 70, 1682-1684	3.4	11
49	Nucleation and initial growth of bias-assisted HFCVD diamond on boron nitride films. *Diamond and Related Materials*, **1997**, 6, 579-583	3.5	20
48	Nucleation and initial growth of diamond by biased hot filament chemical vapour deposition. *Applied Physics A: Materials Science and Processing*, **1997**, 65, 241-249	2.6	18

47	Combined Roles of Ion Bombardment and Electron Emission in Bias-Enhanced Diamond Nucleation on Silicon by Hot Filament Chemical Vapour Deposition. *Physica Status Solidi A*, **1997**, 161, R3-R4		4
46	High-vacuum versus environmental electron beam deposition. *Journal of Vacuum Science & Technology an Official Journal of the American Vacuum Society B, Microelectronics Processing and Phenomena*, **1996**, 14, 2609		52
45	Atomic force microscopy observation of the first stages of diamond growth on silicon. *Diamond and Related Materials*, **1996**, 5, 592-597	3.5	19
44	Internal stress and strain in heavily boron-doped diamond films grown by microwave plasma and hot filament chemical vapor deposition. *Journal of Applied Physics*, **1996**, 80, 1846-1850	2.5	56
43	Carbon nitride thin films obtained by laser ablation of graphite in a nitrogen plasma. *Applied Surface Science*, **1996**, 96-98, 870-873	6.7	15
42	Structural modeling of the possible growth of oriented textured single-crystal diamond film on a silicon (111) surface. *Applied Physics Letters*, **1996**, 69, 1086-1088	3.4	15
41	Laser wavelength dependence of YBa2Cu3Oy laser ablation plumes. *Applied Surface Science*, **1995**, 86, 59-63	6.7	4
40	Pulsed laser deposition of diamond from graphite targets. *Applied Physics Letters*, **1995**, 67, 485-487	3.4	42
39	Characterization of hydroxyapatite laser ablation plumes by fast intensified CCD-imaging. *Journal of Materials Research*, **1995**, 10, 473-478	2.5	15
38	CVD diamond films on bio-medical ceramics. *Diamond and Related Materials*, **1995**, 4, 798-801	3.5	5
37	Evolution of the plumes produced by laser ablation of a carbon target. *Diamond and Related Materials*, **1995**, 4, 337-341	3.5	8
36	Growth of diamond by laser ablation of graphite. *Diamond and Related Materials*, **1995**, 4, 780-783	3.5	13
35	Comparative study of trimethylboron doping of hot filament chemically vapour deposited and microwave plasma chemically vapour deposited diamond films. *Thin Solid Films*, **1994**, 253, 136-140	2.2	6
34	Comparative study of high corrosion resistant TiCxN1-x and TiN hard coatings. *Surface and Coatings Technology*, **1994**, 68-69, 536-540	4.4	16
33	Microstructural analysis of CAPD Ti(C,N) hard coatings. *Vacuum*, **1994**, 45, 1001-1002	3.7	
32	Boron incorporation effects in CVD diamond film growth. *Vacuum*, **1994**, 45, 1013-1014	3.7	12
31	Interfacial layer effects in the growth of CVD diamond. *Diamond and Related Materials*, **1994**, 3, 492-494	3.5	14
30	Trimethylboron doping of CVD diamond thin films. *Diamond and Related Materials*, **1994**, 3, 628-631	3.5	41

29	Spectroscopic ellipsometry measurements of the diamond-crystalline Si interface in chemically vapour-deposited polycrystalline diamond films. *Diamond and Related Materials*, **1993**, 2, 728-731	3.5	5
28	Structural characterization of a-SiC:H by thermal desorption spectroscopy. *Applied Surface Science*, **1993**, 70-71, 768-771	6.7	4
27	Effect of methane/hydrogen dilution on the properties of hydrogenated amorphous carbon films deposited by RF-plasma. *Diamond and Related Materials*, **1992**, 1, 538-542	3.5	5
26	Analysis of contamination in diamond films by secondary ion mass spectroscopy. *Diamond and Related Materials*, **1992**, 1, 500-503	3.5	17
25	Product analysis from D2O electrolysis with Pd and Ti cathodes. *Electrochimica Acta*, **1992**, 37, 215-219	6.7	9
24	Hydrogen related effects in a-Si:H studied by photothermal deflection spectroscopy. *Physica B: Condensed Matter*, **1991**, 170, 269-272	2.8	6
23	Structure characterization of plasma-deposited TiN coatings. *Surface and Coatings Technology*, **1991**, 45, 67-72	4.4	11
22	Ellipsometric study of diamond-like thin films. *Surface and Coatings Technology*, **1991**, 47, 263-268	4.4	26
21	Plasma deposition of hydrogenated amorphous carbon (a-C:H) under a wide bias potential range. *Surface and Coatings Technology*, **1991**, 47, 89-97	4.4	21
20	Surface reflectivity of TiN thin films measured by spectral ellipsometry. *Surface Science*, **1991**, 251-252, 200-203	1.8	12
19	Real time controlled rf reactor for deposition of a-Si:H thin films. *Vacuum*, **1989**, 39, 795-798	3.7	34
18	Hydrogenated amorphous silicon films obtained by a low pressure dc glow discharge. *Applied Physics A: Solids and Surfaces*, **1988**, 46, 207-213		2
17	Distribution of electron energy in an electrostatically confined silane plasma. *Journal of Applied Physics*, **1988**, 63, 1230-1232	2.5	5
16	Electrostatic confinement effects on a hot cathode DC glow discharge in silane. *Journal Physics D: Applied Physics*, **1987**, 20, 1479-1483	3	3
15	Rheotaxial growth of CuInSe2 thin films. *Journal of Vacuum Science and Technology A: Vacuum, Surfaces and Films*, **1987**, 5, 169-173	2.9	2
14	Glow discharge deposited a-Si:H,Al thin films. *Solar Energy Materials and Solar Cells*, **1987**, 15, 167-173		3
13	Deposition of amorphous silicon films from an electrostatically confined silane plasma. *Vacuum*, **1987**, 37, 443-444	3.7	
12	Optical properties of co-evaporated CuInSe2thin films. *Journal Physics D: Applied Physics*, **1986**, 19, 127-136	3	33

11	Temperature dependence of intergrain barriers in polycrystalline In-doped CdS films. *Solid-State Electronics*, **1985**, 28, 1019-1023	1.7	6
10	Dependence of transport parameters on thickness in polycrystalline CdS thin films. *Thin Solid Films*, **1985**, 123, 297-306	2.2	17
9	Indium thin films on metal-coated substrates. *Thin Solid Films*, **1985**, 129, 103-109	2.2	6
8	Crystalline properties of co-evaporated CuInSe2 thin films. *Thin Solid Films*, **1985**, 130, 155-164	2.2	21
7	Filament discharge plasma of argon with electrostatic confinement. *Journal Physics D: Applied Physics*, **1985**, 18, 1339-1345	3	10
6	Electrical conductivity of polycrystalline CuInSe2thin films. *Journal Physics D: Applied Physics*, **1984**, 17, 2423-2427	3	16
5	Electron tunneling in heavily In-doped polycrystalline CdS films. *Journal of Applied Physics*, **1984**, 56, 1738-1743	2.5	46
4	Electrical properties of polycrystalline In-doped CdS thin films. *Journal Physics D: Applied Physics*, **1984**, 17, 1679-1685	3	17
3	Optical properties of vacuum-evaporated CdTe thin films. *Thin Solid Films*, **1984**, 120, 23-30	2.2	53
2	Rheotaxial growth on indium thin films. *Thin Solid Films*, **1984**, 113, L21-L23	2.2	3
1	Indium liquid films on glass substrates. *Thin Solid Films*, **1983**, 103, L51-L54	2.2	2